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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Randy Skocytec et al.

Serial No.: 10/622,307

Filed: July 18, 2003

For: Cleaning Semiconductor
Wafers

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Art Unit: 1746

Examiner: Bibi Sharidan Carrillo

Docket: ITL.1017US
P16704

Assignee: Intel Corporation

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO FINAL REJECTION

Sir:

In response to the final rejection mailed January 4, 2005, reconsideration is requested in view of the following remarks.

Date of Deposit: February 15, 2005

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden
Cynthia L. Hayden